

POLISHING APPARATUS

ABSTRACT OF THE DISCLOSURE

A thickness calculating section 53 calculates the thickness of a platelike workpiece from an optical path difference between light reflected from the upper surface of the workpiece and light reflected from the lower surface of the workpiece. A radiation thermometer 541 detects infrared light radiated from the workpiece to measure the temperature of the workpiece, and a temperature storing section 542 stores the temperature measured by the radiation thermometer 541. A thickness correcting section 55 calculates the refractive index of the workpiece according to the temperature stored by the temperature storing section 542 and then corrects the thickness calculated by the thickness calculating section 53, according to the refractive index calculated above. In this manner, the workpiece is polished as the measurement of the thickness of the workpiece and the correction of the thickness measured are performed until the thickness of the workpiece becomes a desired thickness.

(Figure 1)